

FORM PTO-1449 (Modified)

LIST OF PATENTS AND PUBLICATIONS FOR  
APPLICANT'S INFORMATION DISCLOSURE  
STATEMENT (Use several sheets if necessary)

Attorney Docket No.: 016301-041700US

Application No.: Unassigned

Applicant: Tony S. Kaushal, et al.

Filing Date: Herewith

Group: Unassigned

JCB728.S. PTO  
09/92/244

08/10/01

## Reference Designation

## U.S. PATENT DOCUMENTS

Page 1

Examiner Initial	Document No.	Date	Name	Class	Sub-class	Filing Date (If Appropriate)
<u>JD</u> AA	5,013,578	05/07/1991	Brown et al.	427	37	12/11/1989
<u>JD</u> AB	5,476,691	12/19/1995	Komvopoulos et al.	427	527	09/15/1994
___ AC						
___ AD						

## FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Class	Sub-class	Translation (Yes/No)
<u>JD</u> AE	JP8074036	03/19/1996	Japan	C23C14	14	Abstract only
<u>JD</u> AF	05-012828	01/28/1993	Japan	C23C14	06	
___ AG						
___ AH						
___ AI						
___ AJ						

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

<u>JD</u> AK	Anders, et al., "Plasma Distribution of Cathodic Arc Deposition Systems", J. Appl. Phys. 79 (9), May, 1996, pp. 6785-6790.
<u>JD</u> AL	Brown, et al., "Development of a DC, Broad Beam, Mevva Ion Source", Rev. Sci. Instrum. 63 (4), April, 1992, pp. 2417-2419.
<u>JD</u> AM	Brown, "Metal Ion Implantation for Large Scale Surface Modification", J. Vac. Sci. Technol. A. Vol. 11, No. 4, Jul/Aug., 1993, pp. 1480-1485.
<u>JD</u> AN	Brown et al., "Multiply Stripped Ion Generation in the Metal Vapor Vacuum Arc", J. Appl. Phys. 63 (10), May, 1988, pp. 4889-4898.
<u>JD</u> AO	Brown, "Vacuum Arc Ion Charge-State Distributions", IEEE Transactions on Plasma Science, Vol. 19, No. 5, October, 1991, pp. 713-717.
<u>JD</u> AP	Brown, "Vacuum Arc Ion Sources", Rev. Sci. Instrum. 65 (10), October, 1994, pp. 3061-3081.
<u>JD</u> AQ	Brown, et al., "Broad-Beam Multi-Ampere Metal Ion Source", Rev. Sci. Instrum. 61 (1), January, 1990, pp. 577-579.
<u>JD</u> AR	Sasaki, "Ion Spectra of Vacuum Arc Plasma with Compound and Alloy Cathodes", J. Appl. Phys. 66 (11), December, 1989, pp. 5198-5203.

EXAMINER

DATE CONSIDERED

9/17/02

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.